

In the United States Patent and Trademark Office

| Applicant: Adrian KIERMASZ |) |
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| •• |) Examiner: M. Rachuba |
| Applicant's Reference: LAM2P452 |) |
| 1 |) Group Art Unit: 3723 |
| Application No. 10/743,923 |) Deter Jame 12, 2006 |
| Filed: December 22, 2003 |) Date: June 13, 2006 |
| riled. December 22, 2005 |) Conf. No. 9016 (Notice of |
| Title: LINEAR CHEMICAL MECHANICAL |) Allowance mailed 03/13/06) |
| PLANARIZATION (CMP) SYSTEM AND |) |
| METHOD FOR PLANARIZING A WAFER |) |
| IN A SINGLE CMP MODULE |) |

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on June 13, 2006.

Signed:

Separate Letter to the Official Draftsperson

Commissioner for Patents Post Office Box 1450 Alexandria, VA 22313-1450

Dear Sir:

Applicant hereby attaches four (4) sheets of formal replacement drawings (Figures 1, 2A, 2B, and 3A-3C) for the above-identified patent application. In the event the Draftsperson has any questions concerning the formal drawings, he or she is respectfully requested to contact the undersigned. If any fees are due in connection with the filing of these drawings, then please charge such fees to our Deposit Account No. 50-0805 (Order No. <u>LAM2P452</u>).

Respectfully submitted,
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